

SIMTEK6598

IN THE UNITED STATES PATENT OFFICE

In re Application of
Kunio Miyazaki
Tomoyuki Kawano
Kazuya Tokunaga
Ichiro Ikenaga

App. No.: 10/709217
Filed: April 22, 2004
Conf. No.: 3216
Title: CONTROL METHOD FOR
MOVING RACKS
Examiner: D. Pihulic
Art Unit: 3662
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

In response to the Office Action, dated August 14, 2007, please amend this application, as follows:

IN THE SPECIFICATION

Amend Paragraph [0035], as follows:

[0035] Amended. Then, operation line error measurement is performed at the step S3. The operation line error measurement is not required when the moving rack is a type which moves along guide rails. However it is necessary for a moving rack which has an endless track type running device and with which guide rails are not required. If the rack has moved obliquely before correction it ~~may~~ may be displaced transversely from the desired parallel path of movement. This is done by comparison with a scanning operation line marked on the floor surface on which an moving rack is installed or on a wall or ceiling above the moving rack to determine a tracing error of the moving rack with respect to the operation line.